

## Special Issue

# III-V Optoelectronics and Semiconductor Process Technology

### Message from the Guest Editors

The Special Issue "III-V Optoelectronics and Semiconductor Process Technology" in the Journal *Micromachines* invites high-quality contributions from both academia and industry. The topics covered include the epitaxial growth and fabrication of III-V semiconductors, device design and characterization, novel device concepts, and process technology for III-V-based devices. The Special Issue also covers the use of III-V materials in various applications, such as LEDs, lasers, photovoltaic cells, and sensors. We look forward to receiving your submissions to this Special Issue.

### Guest Editors

Dr. Hsin-Chu Chen

Prof. Dr. Hao-Chung Kuo

Prof. Dr. Yi-Jen Chiu

### Deadline for manuscript submissions

closed (31 July 2024)



## Micromachines

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## About the Journal

### Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

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